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MCDERMOTT, WILL & EMERY
600 13th Street, N.W.
Washington, DC 20005-3096

EXAMINER

ARENA, ANDREW OWENS

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PAPER

Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

DETAILED ACTION

Response to Arguments

The arguments filed 5/12/2008 were fully considered but are not persuasive.

The argument that “Inoguchi also fails to disclose...a seed layer” is not convincing since the term “seed” must be interpreted per MPEP § 2111 and reads on at least one of the several layers disclosed by Inoguchi.

The only feature of the claimed invention that is arguably missing from Inoguchi is an explicit teaching that said epitaxial layers are of the 4H-type, the advantages of which are taught by Onojima.

Claim Rejections - 35 USC § 103

Claims 2, 3, 5 and 51-59 are rejected under 35 U.S.C. 103(a) as being obvious in view of Inoguchi (US 5,900,647) and Onojima (Appl. Phys. Lett., V.83, N.25, pg 5208).

RE claim 51, Inoguchi discloses an optoelectronic device (Fig 4, col 8 ln 28-33; Fig 6, col 11 ln 60-65) comprising,

a first III-V Nitride semiconductor epitaxial film (83) formed in contact with a substrate (21/22, 81/82) having 4H-type structure (col 10 ln 36-38), wherein said first III-V Nitride semiconductor epitaxial film is a AlN film (col 12 ln 29-30), and

a seed layer (84) of III-V Nitride (GaN: col 12 ln 33) selectively formed on said first III-V Nitride semiconductor epitaxial film, wherein said seed layer contains Ga, and

a second III-V Nitride semiconductor epitaxial film (23-26, col 8; 85-88, col 12) formed on said first III-V Nitride semiconductor epitaxial film, wherein said second III-V Nitride semiconductor epitaxial film contains Ga and is in contact with said seed layer.

Inoguchi differs from the claimed invention only in not expressly disclosing the polytype of said III-V Nitride films.

Onojima teaches that high-performance devices may be realized with 4H-AlN on 4H-SiC substrates (e.g., pg 5210 col 2 ln 13-16) and further teaches such arrangements are desirable in the art due to certain appreciated advantages (pg 5208 col 1 ln 1-4).

It would have been obvious to a person having ordinary skill in the art at the time the invention was made that said III-V Nitride films are 4H films; at least for the advantages of such arrangement. Also see MPEP § 2144.06-2144.07.

RE claim 2, Inoguchi discloses the substrate is silicon carbide (col 8 ln 38).

RE claim 3, the combined teachings relied upon disclose said III-V Nitride semiconductor epitaxial film is formed in contact with a substrate having (11-20) face (Onojima: pg 5210 col 2 ln 3).

RE claim 5, Inoguchi discloses a number of group III atoms are equal to a number of nitrogen atoms on a surface of said III-V Nitride semiconductor epitaxial film. Inoguchi discloses same composition; claimed property inherent. MPEP § 2112.01(II).

RE claim 52, Inoguchi discloses an optoelectronic device (Fig 4, col 8 ln 28-33) comprising,

a first III-V Nitride semiconductor epitaxial film (83) selectively formed in contact with a substrate (21/22, 81/82) having 4H-type structure (col 10 ln 36-38);

a seed layer (84) of III-V Nitride (GaN: col 12 ln 33) selectively formed on said first III-V Nitride semiconductor epitaxial film,

a second III-V Nitride semiconductor epitaxial film (23-26, col 8 ln 53-58; 85-88, col 12) formed on said first III-V Nitride semiconductor epitaxial film; and

a waveguide (31; col 9 ln 44, col 8 ln 20, 111) formed on said second III-V Nitride semiconductor epitaxial film,

wherein said first III-V Nitride semiconductor film is an AlN film (col 12 ln 29), said seed layer contains Ga (col 12 ln 33),

said second III-V Nitride semiconductor film contains Ga and is in contact with said seed layer, and

said second III-V Nitride semiconductor epitaxial film includes an n-type layer (23, col 8 ln 59; 87/88, col 12 ln 51-58), a p-type layer (26, col 9 ln 10; 84/85, col 12 lns 33 & 66) and an active layer (25, col 9 ln 4-5; 86, col 12 ln 43-46), said active layer being formed between said n-type layer and said p-type layer.

Inoguchi differs from the claimed invention only in not expressly disclosing the polytype of said III-V Nitride semiconductor epitaxial films.

Onojima teaches that high-performance devices may be realized with 4H-AlN on 4H-SiC substrates (e.g., pg 5210 col 2 ln 13-16) and further teaches such arrangements are desirable in the art due to certain appreciated advantages (pg 5208 col 1 ln 1-4).

It would have been obvious to a person having ordinary skill in the art at the time the invention was made that said III-V Nitride semiconductor epitaxial films are 4H films; at least for the advantages of such arrangement. Also MPEP § 2144.06-2144.07.

RE claim 53, Inoguchi discloses a plurality of layers (23-26) are disposed between said waveguide (31) and said substrate (21).

RE claim 54, Inoguchi discloses said substrate having 4H [poly]type structure is SiC (col 10 ln 36-38).

RE claim 55, the combined teachings relied upon disclose said III-V Nitride semiconductor epitaxial film is formed in contact with a substrate having (11-20) face (Onojima: pg 5210 col 2 ln 3).

RE claim 56, the combined teachings relied upon disclose a number of group III atoms are equal to a number of nitrogen atoms on a surface of said III-V Nitride semiconductor epitaxial film. Onojima discloses same composition; claimed property inherent. MPEP § 2112.01(II).

RE claim 57, the combined teachings relied upon disclose said waveguide is formed as a straight line perpendicular to either (0001) face or (1-100) face (Inoguchi Fig 4 shows said stripe is perpendicular to the substrate face; the combination discloses the substrate face is (11-20), so the stripe must be perpendicular to either claimed face, since they are the two remaining axes, e.g. Onojima Fig 3 or applicant's Fig 2-4).

RE claims 58 & 59, Inoguchi discloses all the structure implied by the process recitations of these claims. See MPEP § 2113.

Conclusion

THIS ACTION IS MADE FINAL. Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the mailing date of this final action.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Andrew O. Arena whose telephone number is (571)272-5976. The examiner can normally be reached on M-F 8:30-5.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Lynne A. Gurley can be reached on 571- 272-1670. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. For more info about PAIR, see <http://pair-direct.uspto.gov>. For questions PAIR access, contact the Electronic Business Center at 866-217-9197 (toll-free). For assistance from a USPTO Customer Service Rep or access to the automated info system, call 800-786-9199 or 571-272-1000.

/Andrew O. Arena/
Examiner, Art Unit 2811
2 September 2008

/Lynne A. Gurley/
Supervisory Patent Examiner, Art
Unit 2811